

CERTIFICATE OF MAILING BY FIRST CLASS MAIL (37 CFR 1.8)

Applicant(s): **GEUN-YOUNG YEOM, ET AL.**

Docket No.

HNE-0001

Serial No.

10/010,548

Filing Date

11/08/2001

MAR 10 2004

Examiner

Tran, Binh X.

Group Art Unit

1765

Invention: **METHOD OF ETCHING SEMICONDUCTOR DEVICE USING NEUTRAL BEAM AND APPARATUS FOR ETCHING THE SAME**

I hereby certify that this **Response to Office Action; Limited Recognition under 37 CFR Section 10.9(b)**

(Identify type of correspondence)

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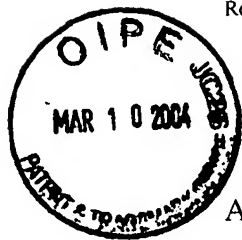
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT:	Geun-Young Yeom, et al.) Examiner:
) Tran, Binh X.
SERIAL NO.:	10/010,548)
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FILED:	November 8, 2001) Art Unit:
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FOR:	METHOD OF ETCHING)
	SEMICONDUCTOR DEVICE USING)
	NEUTRAL BEAM AND APPARATUS)
	FOR ETCHING THE SAME)

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Commissioner for Patents
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AMENDMENT

Dear Sir:

Applicants respectfully request entry of the following amendment and remarks contained herein in response to the Office Action mailed January 7, 2004. Applicants respectfully submit that the amendment and remarks contained herein place the instant application in condition for allowance.